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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Chung, et al. §
Serial No.: 09/963,373 § Group Art Unit: 2814
Confirmation No.: 6509 §
Filed: September 26, 2001 §
For: INTEGRATION OF § Examiner: Wai Sing Louie
BARRIER LAYER AND §
SEED LAYER §

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING 37 CFR 1.8	
I hereby certify that this correspondence is being deposited on August 31, 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.	
8/31/04	
Date	Signature

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

The Applicants, and the Attorney who signs below on the basis of the information supplied by the inventor and the information in his file, submit herewith patents, publications, or other information of which they are aware, which may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

While the information submitted in this Supplemental Information Disclosure Statement may be material pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication, or other information referred to therein is prior art for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97, this Supplemental Information Disclosure Statement is not to be construed as a representation that a search has been made or that no other possibly material information as defined under 37 CFR § 1.56(a) exists.

The patents and/or publications submitted herewith are set forth on the attached Form PTO-1449.

If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/6303.02/KMT.

Respectfully submitted,



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Attorney for Applicant(s)

Substitute for form 1449A/PTO

Application Number 09/963,373

**SUPPLEMENTAL INFORMATION
DISCLOSURE STATEMENT BY
APPLICANT**

(Use as many sheets as necessary)

Filing Date September 26, 2001

First Named Inventor Chung, et al.

Group Art Unit 2814

Examiner Name Wai Sing Louie

Attorney Docket Number AMAT/6303.02/CPICOPPER/PJS

Sheet 1

of

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U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
	A1	US-6686271 B2	02/03/2004	Raaijmakers, et al.	
	A2	US-6660660 B2	12/09/2003	Haukka, et al.	
	A3	US-6632279 B1	10/14/2003	Ritala, et al.	
	A4	US-6630201 B2	10/07/2003	Chiang, et al.	
	A5	US-6620956 B2	09/16/2003	Chen, et al.	
	A6	US-6620723 B1	09/16/2003	Byun, et al.	
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	A28	US-6428859 B1	08/06/2002	Chiang, et al.	

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A29		US-6416822 B1	07/09/2002	Chiang, et al.	
A30		US-6416577 B1	07/09/2002	Suntoloa, et al.	
A31		US-6399491 B2	06/04/2002	Jeon, et al.	
A32		US-6391785 B1	05/21/2002	Satta, et al.	
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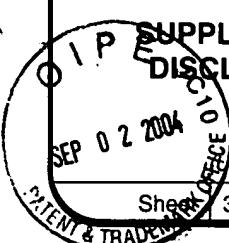
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Sheet 3

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		Number-Kind Code ² (if known)			
	A55	US-20040018304 A1	01/29/2004	Chung, et al.	
	A56	US-20040016866 A1	01/29/2004	Huang, et al.	
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	A140	US-20020106536 A1	08/08/2002	Lee, et al.	
	A141	US-20020106451 A1	08/08/2002	Skarp, et al.	
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	A153	US-20020074588 A1	06/20/2002	Lee	
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	A166	US-20010050039 A1	12/13/2001	Park	

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Application Number

09/963,373

Filing Date

September 26, 2001

First Named Inventor

Chung, et al.

Group Art Unit

2814

Examiner Name

Wai Sing Louie

Attorney Docket Number

AMAT/6303.02/CPICOPPER/PJS

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DISCLOSURE STATEMENT BY
APPLICANT**

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Submission Date

August 31, 2004

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	A168	US-20010025979 A1	10/04/2001	Kim, et al.	
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Application Number	09/963,373
Filing Date	September 26, 2001
First Named Inventor	Chung, et al.
Group Art Unit	2814
Examiner Name	Wai Sing Louie
Attorney Docket Number	AMAT/6303.02/CPICOPPER/PJS
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Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ²
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				
	B16	WO 02/45871 A1	06/13/2002	Chiang, et al.		
	B17	WO 03/044242 A2	05/30/2003	Chen, et al.		

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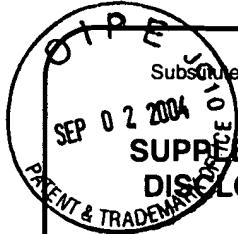
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	C2	Chang-Wook, et al. "Growth and Characterization of Aluminum Oxide (Al ₂ O ₃) Thin Films by Plasma-Assisted Atomic Layer Controlled Deposition," J. Korean Inst. Met. Mater., Vol. 38, No. 10, Oct. 2000 pp.1395-1399	
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Sheet	9	of	9	Submission Date	August 31, 2004
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NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
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